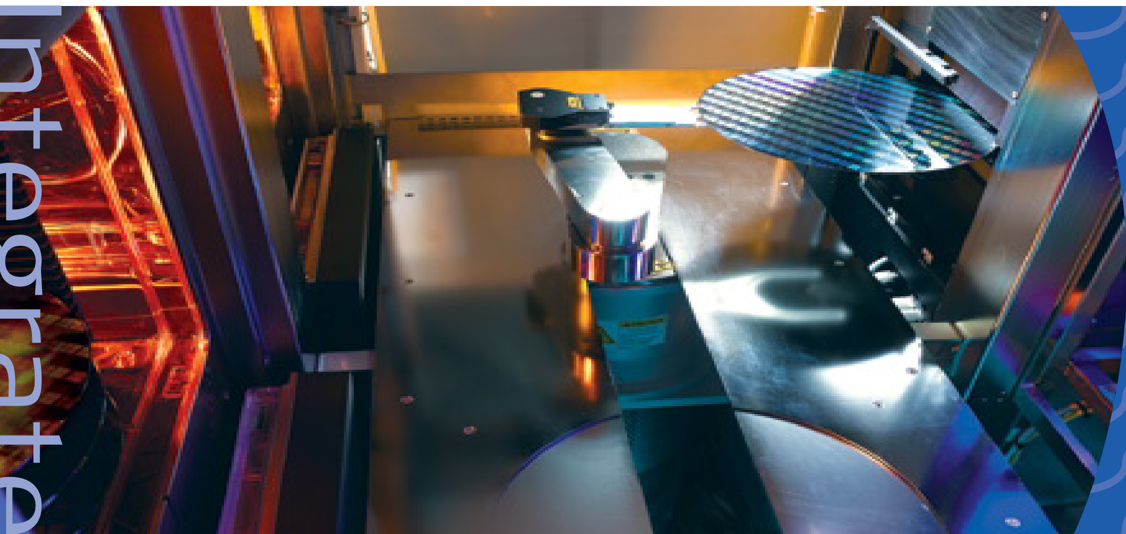
NOVA®

partnering for process control

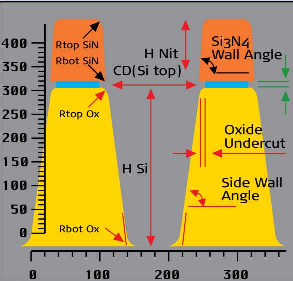
NovaScan 3090CD

Integrated Metrology Solutions



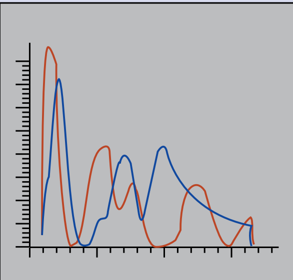
An Advanced Metrology Platform for CD Control and Profile Measurements

- Integrated Metrology and Standalone platform for 200mm and 300mm
- Designed for 90nm and beyond
- High-throughput system for a wide range of Etch and Lithography applications
- Supports 2D and 3D structures, including contact and via applications
- Provides real-time measurement of CD, trench depth, photoresist height, thickness and shape of complex layer stacks



STI profile modeling

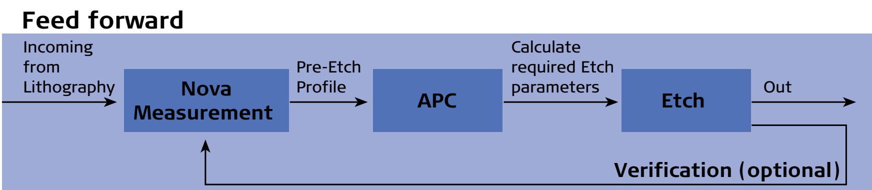
STI Cross-section



STI spectral fit for TE and TM

APC Concept: Feed forward and feed backward

Feed forward



Feed backward